



Atty.
Dkt. No.

M#

Client Ref.

284106

P 0293.000-US

**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Applicant: VAN SCHAIK et al

Application No.: 09/988,391

Filing Date: November 19, 2001

Date: April 16, 2002

Page

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of

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Examiner: Unknown

Group Art Unit: 2878

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
VG	AR	6,252,648	06/2001	HASE et al.			
	BR						
	CR						
	DR						
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	OR									
	PR									
	QR									
	RR									
	SR									
	TR									
	UR									
	VR									
	WR									
	XR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	YR									
	ZR									
	AAR									
	BBR									
	CCR									
	DDR									

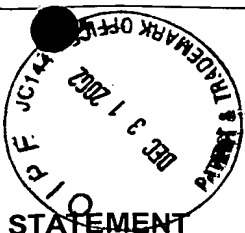
Examiner

Paul Henzo

Date Considered:

5/19/03

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.



Atty. Dkt. No.	M#	Client Ref.
	284106	P-0293.000-US

**INFORMATION DISCLOSURE STATEMENT
 BY APPLICANT**

Applicant: VAN SCHAIK et al

Application No.: 09/988,391

Filing Date: November 19, 2001

Examiner: Unknown Group Art Unit: 2878

Date: December 31, 2002 Page 1 of 1

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
P6	AR 6,387,602	05/2002	HAYDEN et al.	TECHNOLOGY CENTER 2800		
	BR					
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	HR					
	IR					
	JR					

FOREIGN PATENT DOCUMENTS

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
	KR							
	LR							
	MR							
	NR							
	OR							
	PR							
	QR							
	RR							
	SR							
	TR							
	UR							
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OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

WR			
XR			
YR			
ZR			
AAR			
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Examiner Paul Bunzo Date Considered: 5/19/03

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FORM PTO-1449 (modified)
To: U.S. Department of Commerce
(PM&S FORM PAT-1449)
Patent and Trademark Office

Atty.
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M#

Client Ref.

284106

P-0293.000-US

Applicant: VAN SCHAIK et al

Application No.: 09/988,391

Filing Date: November 19, 2001

Examiner: Unknown

Group Art Unit: 2878

Date: September 13, 2002

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Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
PB	AR	6,411,368	06/2002	MATSUMOTO et al.			
	BR						
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	DR						
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	FR						
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	HR						
	IR						
	JR						

FOREIGN PATENT DOCUMENTS

ORIGINAL FILE DOCUMENT							Abstract		Readily Available	
		Document Number	Date MM/YYYY	Country	Inventor Name		Enclosed	No	Enclose	No
PB	KR	0 660 188 A1	06/1995	EUROPE	STRAAIJER et al.					
	LR									
	MR									
	NR									
	OR									
	PR									
	QR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

PB	RR	Bloomstein et al., "UV Cleaning of Contaminated 157-nm Reticles," <i>Proceedings of SPIE</i> 4346:669-375 (2001)			
PB	SR	Liberman, "Reticle Materials Testing Facilities at MIT Lincoln Laboratory," presented March 9, 2000			
PB	TR	Bloomstein et al., "UV Cleaning of Contaminated Reticles," presented August 1, 2000			
PB	UR	Bloomstein et al., "Studies of Laser Induced Contamination and Cleaning," presented November 21, 2000			
PB	VR	Bloomstein et al., "Optical Materials and Coatings at 157 nm," <i>Proceedings of SPIE</i> 3676:342-349 (1999)			
PB	WR	Bloomstein et al., "Laser Cleaning of Optical Elements in 157-nm Lithography," <i>Proceedings of SPIE</i> 4000:1537-1545 (2000)			
PB	XR	Bloomstein et al., "Controlled Contamination of Optics Under 157-nm Laser Irradiation," <i>Proceedings of SPIE</i> 4346:685-694 (2001)			

Examiner

Paul Surgo

Date Considered:

5/19/03

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